# **Special Issue**

# Emerging Trends in Artificial Intelligence and Machine Learning for Advanced Collaborative Manufacturing Systems

# Message from the Guest Editors

The Special Issue "Emerging Trends in Artificial Intelligence and Machine Learning for Advanced Collaborative Manufacturing Systems" is online! This Special Issue aims to serve as a platform for researchers and practitioners to showcase cutting-edge developments, applications, and advancements in the use of Al and ML in manufacturing applications. By showcasing innovative research and case studies, this issue seeks to emphasize how these technologies are shaping the future of manufacturing.

### **Guest Editors**

Dr. Valentina De Simone

Dr. Valentina Di Pasquale

Dr. Raffaele lannone

Dr. Fabio Fruggiero

# Deadline for manuscript submissions

28 February 2026

01010 01010 01010

# Information

an Open Access Journal by MDPI

Impact Factor 2.9 CiteScore 6.5



mdpi.com/si/233506

Information
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
information@mdpi.com

mdpi.com/journal/information



# 01010 01010 01010

# Information

an Open Access Journal by MDPI

Impact Factor 2.9 CiteScore 6.5



# **About the Journal**

# Message from the Editor-in-Chief

The concept of *Information* is to disseminate scientific results achieved via experiments and theoretical results in depth. It is very important to enable researchers and practitioners to learn new technology and findings that enable development in the applied field.

Information is an online open access journal of information science and technology, data, knowledge and communication. It publishes reviews, regular research papers and short communications. We invite high quality work, and our review and publication processing is very efficient.

### Editor-in-Chief

# Prof. Dr. Willy Susilo

School of Computer Science and Software Engineering, University of Wollongong, Northfields Avenue, Wollongong, NSW 2522, Australia

### **Author Benefits**

# Open Access:

free for readers, with article processing charges (APC) paid by authors or their institutions.

### **High Visibility:**

indexed within Scopus, ESCI (Web of Science), Ei Compendex, dblp, and other databases.

# Journal Rank:

JCR - Q2 (Computer Science, Information Systems) / CiteScore - Q2 (Information Systems)

